



Comprendre le monde,
construire l'avenir



Towards the construction of the new ATLAS inner detector for the HL-LHC upgrade

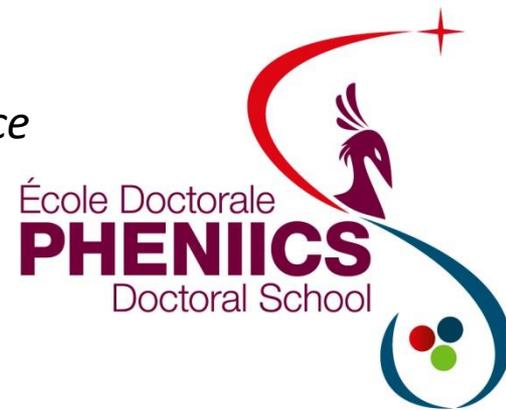
Dmytro HOHOV

Laboratoire de L'accélérateur Linéaire, Orsay, France

Université Paris-SUD XI



PHENIICS Fest - 28-29 mai 2018

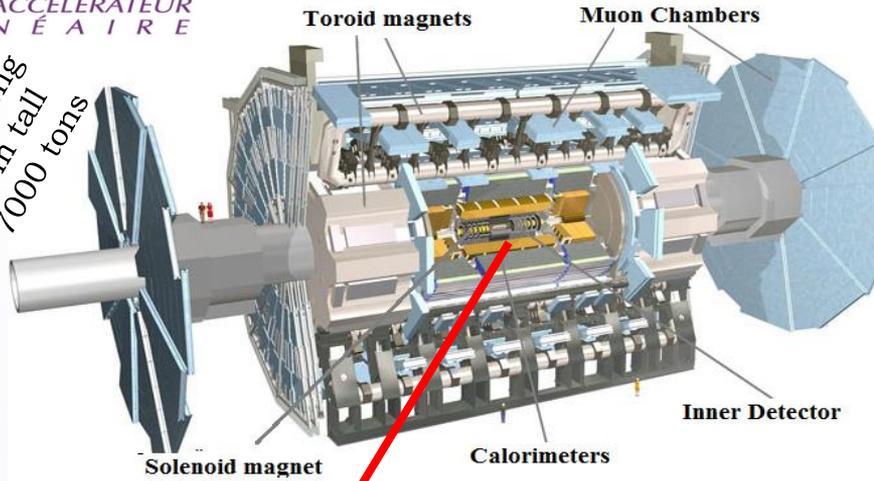


Outline

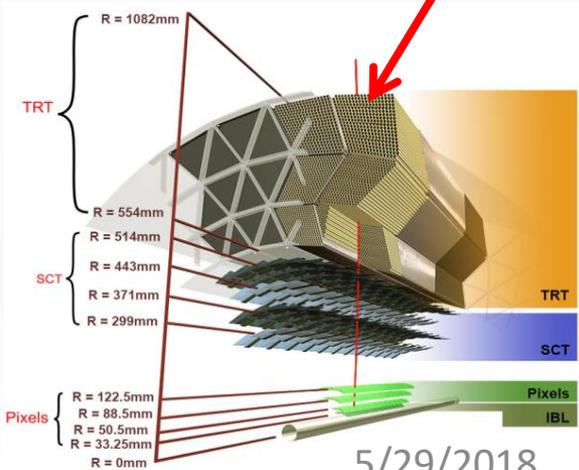
- **ATLAS project**
 - Structure of the ATLAS detector
 - ATLAS detector upgrade connected with HL-LHC project
- **Pixel detectors**
 - Working principle of pixel detectors
 - Current and future concepts of pixel detectors
- **Tests and characterization as an important stage in the pixel detector development**
 - Module characterization at test beam facilities
 - Characterization in the clean room
 - LAL participation in Demonstrator project
- **Conclusions**

ATLAS detector

44 m long
25 m tall
7000 tons



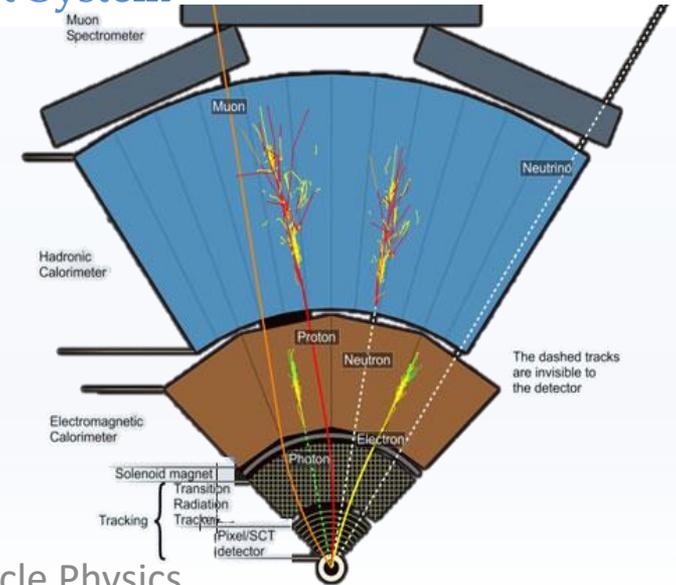
- **Inner Detector** (measures the momentum of charged particles)
- **Calorimeter** (measures the energies carried by particles)
- **Muon Spectrometer** (Identifies and measures muons)
- **Magnet System**



Transition Radiation Tracker

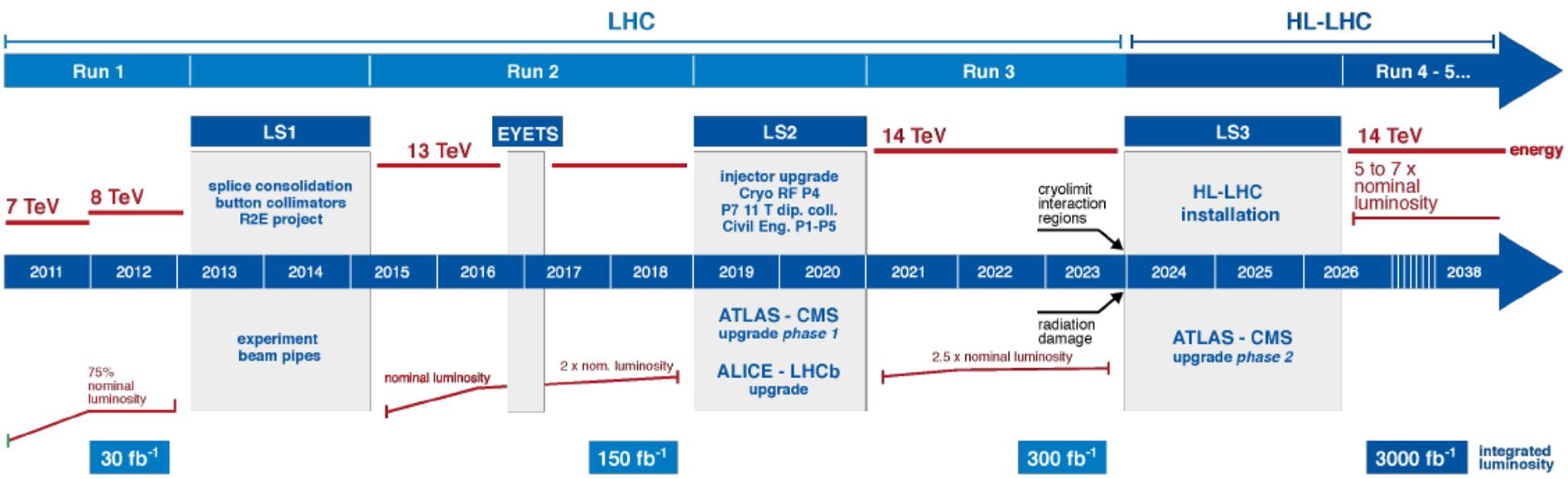
Semi-Conductor Tracker

Pixel Detector



The (HL-)LHC Timeline

LHC / HL-LHC Plan



Motivation for ATLAS Inner Detector upgrade

Name of the upgrade	Date	Luminosity	Energy \sqrt{s}
LHC startup	2009	$6 \times 10^{33} \text{ cm}^{-2}\text{s}^{-1}$	7-8 TeV
Phase- 0	2014	$1 \times 10^{34} \text{ cm}^{-2}\text{s}^{-1}$	13 TeV
Phase- 1	2018	$2 \times 10^{34} \text{ cm}^{-2}\text{s}^{-1}$	13-14 TeV
Phase- 2	2023	$7,5 \times 10^{34} \text{ cm}^{-2}\text{s}^{-1}$	14 TeV

Very severe pile-up conditions expected:



Corresponding num. of inelastic **pp** collisions per beam-crossing (25 ns) will increase : **25 -> 200**

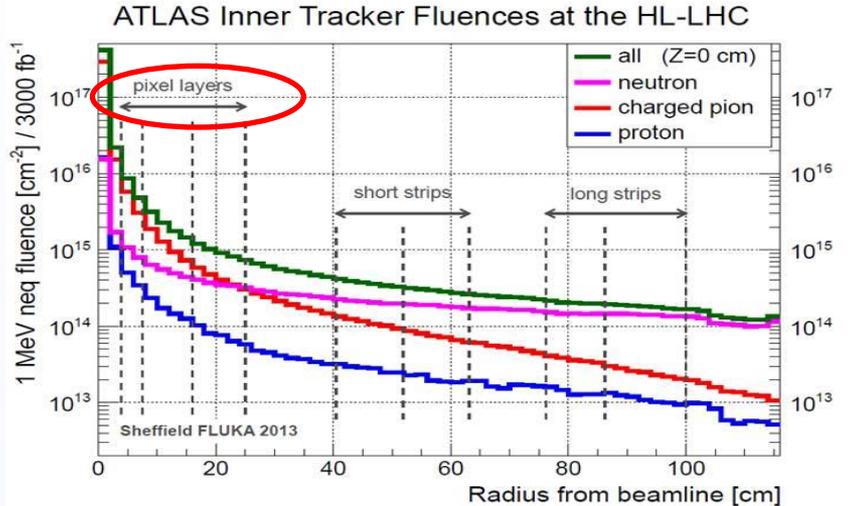
New Tracking detectors must fulfill the conditions:

- Fast (40MHz), high granularity & good pattern recognition capabilities (10^3 tracks/25 ns).



Motivation for ATLAS Inner Detector upgrade

- Increased luminosity also leads to increasing of radiation load.



Aim is **3-4k fb⁻¹** integrated luminosity

ID (Inner Detector) has limited lifetime:

Expected:
 $1.6 \cdot 10^{16} n_{eq} cm^{-2}$

➔ **1.7 GRad**

Designed:
 $10^{14} n_{eq} cm^{-2}$

➔ estimated to correspond to
400 fb⁻¹

Radiation Effects:

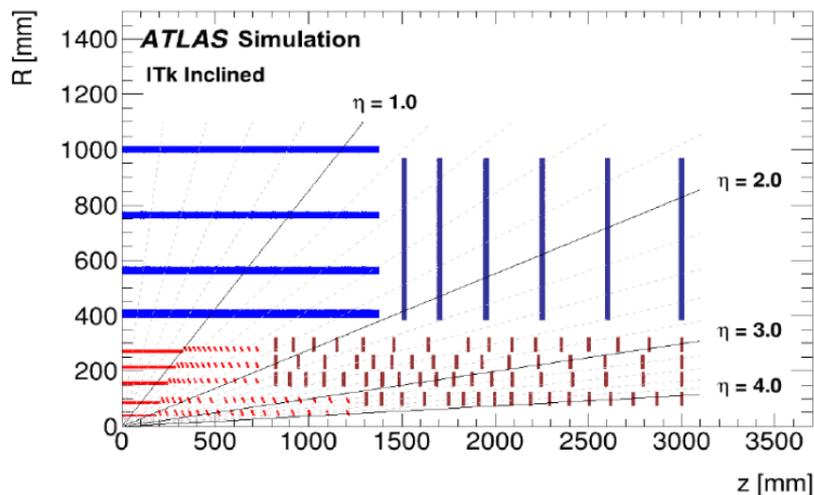
- Creation of lattice defects (loss in the charge collection due to charge capture).
- Change of depletion voltage (due to type inversion).
- Rise of leakage current (additional energy levels are being formed in the band gap region)

Motivation for ATLAS Inner Detector upgrade

The new All Silicon Inner Tracker (ITk), ~ 10 years operational, Strips and Pixels



Layout for the Phase-II Inner Tracker (Apr 2017)

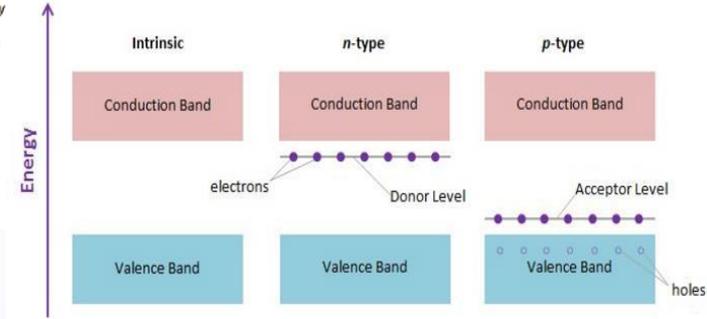
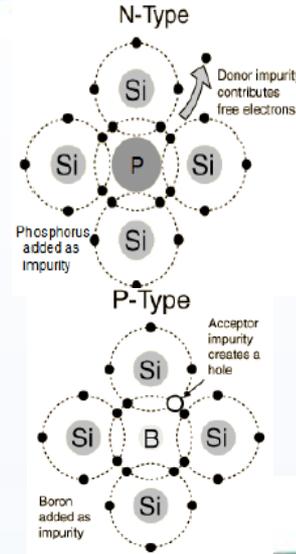
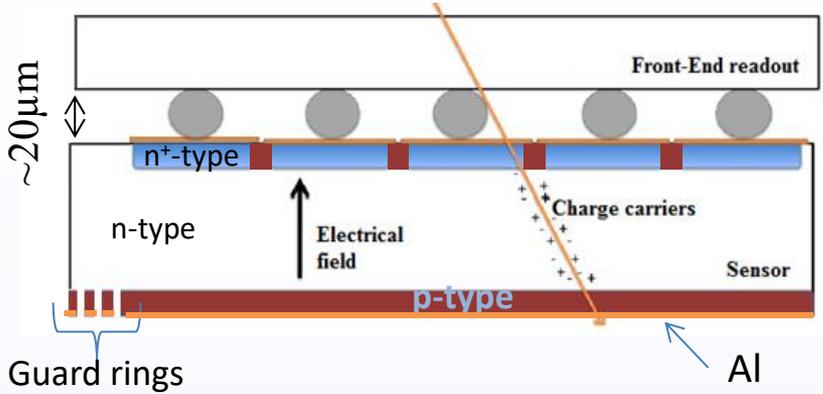


	Silicon Area	Channels [10^6]
Pixel	~13 m ²	580
Strip	160 m ²	50

- The target acceptance has been extended to ± 4 units of pseudorapidity
- Pixel system extending to roughly twice the radius and four times the length
- Reduced material budget before calorimeters

Working principle of pixel detectors

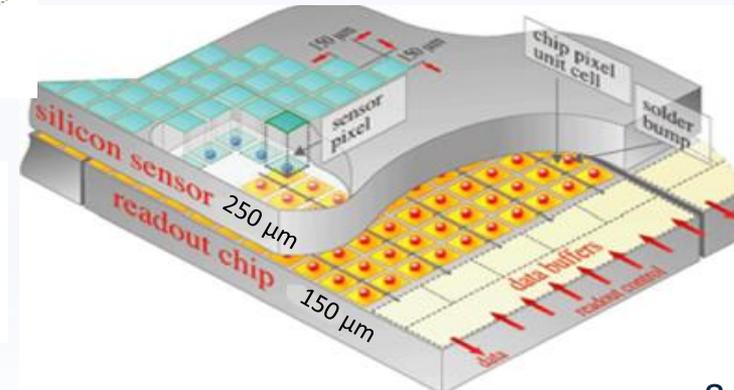
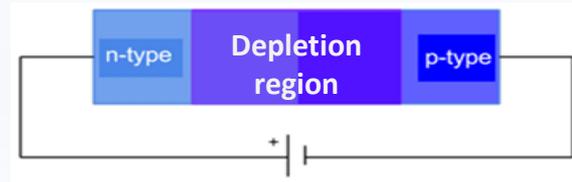
Hybrid planar pixel detector:



To operate, the semiconductor (silicon) must be depleted:

Full charge collection only for
($V_{\text{bias}} > V_{\text{dep}}$)

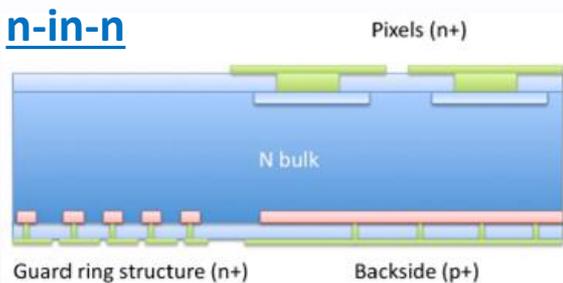
reverse biased pn-junction



Alternatives for Planar pixel technology

There are two planar sensor configurations that can be used for high particle fluences due to their fast charge collection : **n-in-n** and **n-in-p**.

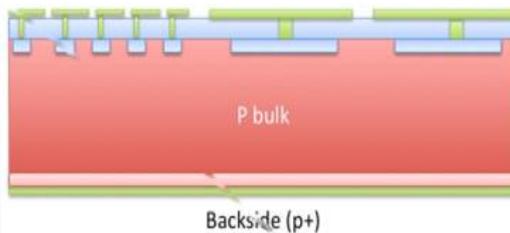
n-in-n



- Collect electrons (3 x faster than holes)
- Guard rings are not on front-end side
- Double-sided processing
- Type inversion of the n-doped silicon bulk

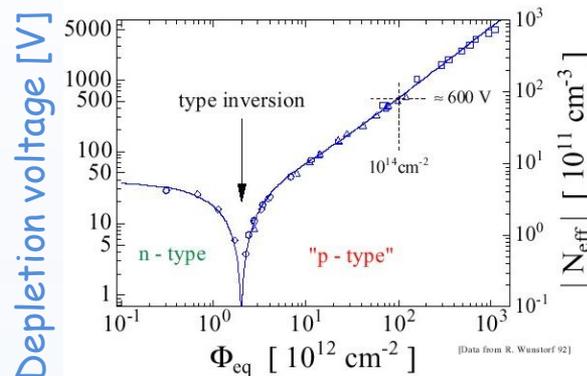
Guard ring structure (n+)

n-in-p



- Collect electrons (3 x faster than holes)
- No type inversion
- Can be operated partially depleted
- Single –sided processing
- Guard rings are on front-end side

Type inversion effect



The change of the effective doping concentration due to irradiation

Alternatives for Planar pixel technology

- **Design parameters to improve:**

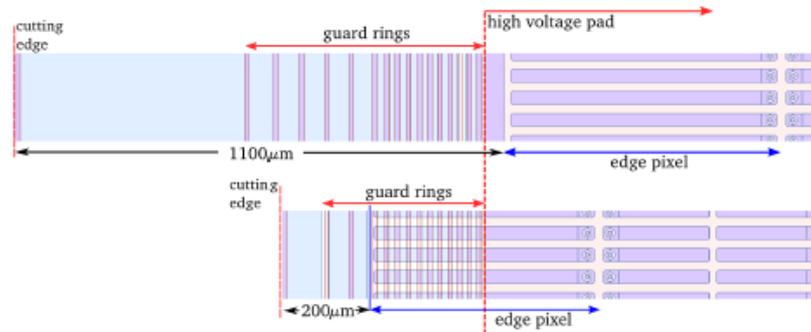
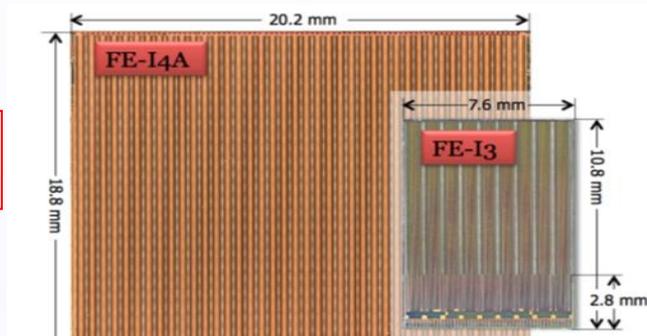
Sensors: the radiation resistance, reducing of non active area (efficiency), thinning, production cost

Electronics: processing speed (dead time), signal-to-noise ratio, reducing of power consumption (cooling), price

Achievements of the Phase 0 (Insertable B-layer) IBL Upgrade:

New Front-End readout chip, designed for the Phase 0

	FE-I3	FE-I4	RD53 A
Pixel size	50x400 μm^2	50x250 μm^2	50x50 μm^2 25x100 μm^2
Pixel matrix	18x160	80x336	
Chip size	7,6x10,8 mm ²	20,0x18,6mm ²	~20x20 mm ²
Technology	250 nm	130 nm	65 nm
Active part	74%	89%	more
Analog current	16 $\mu\text{A}/\text{pixel}$	10 $\mu\text{A}/\text{pixel}$	less
Digital current	10 $\mu\text{A}/\text{pixel}$	10 $\mu\text{A}/\text{pixel}$	Less
Data rate	40 Mb/s	160 Mb/s	2 Gb/s



Planar pixel sensors to test

Samples to study: FE-I4 compatible thin **n-in-p** planar pixel sensors with *the active and slim edge design* produced by ADVACAM.

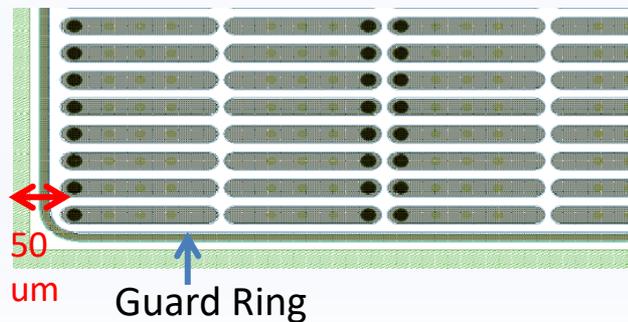
- Radiation hard (no type inversion, thin);
- Single side processing;
- Thickness : 50 μm , 100 μm , 150 μm ;
- Maximized active area (Deep Reactive Ion Etching (DRIE));

It is particularly interesting for the innermost layers where it is important to reduce geometrical inefficiencies.

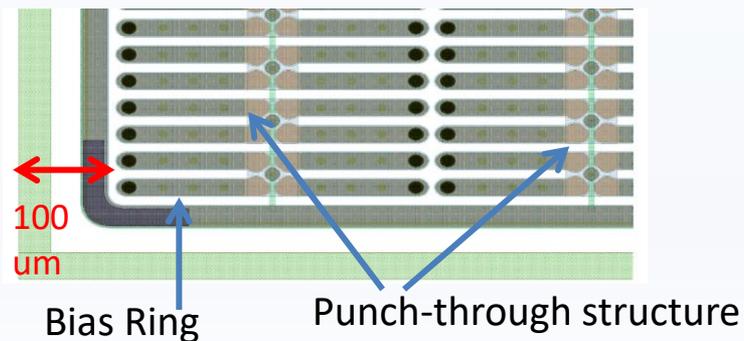
Goal:

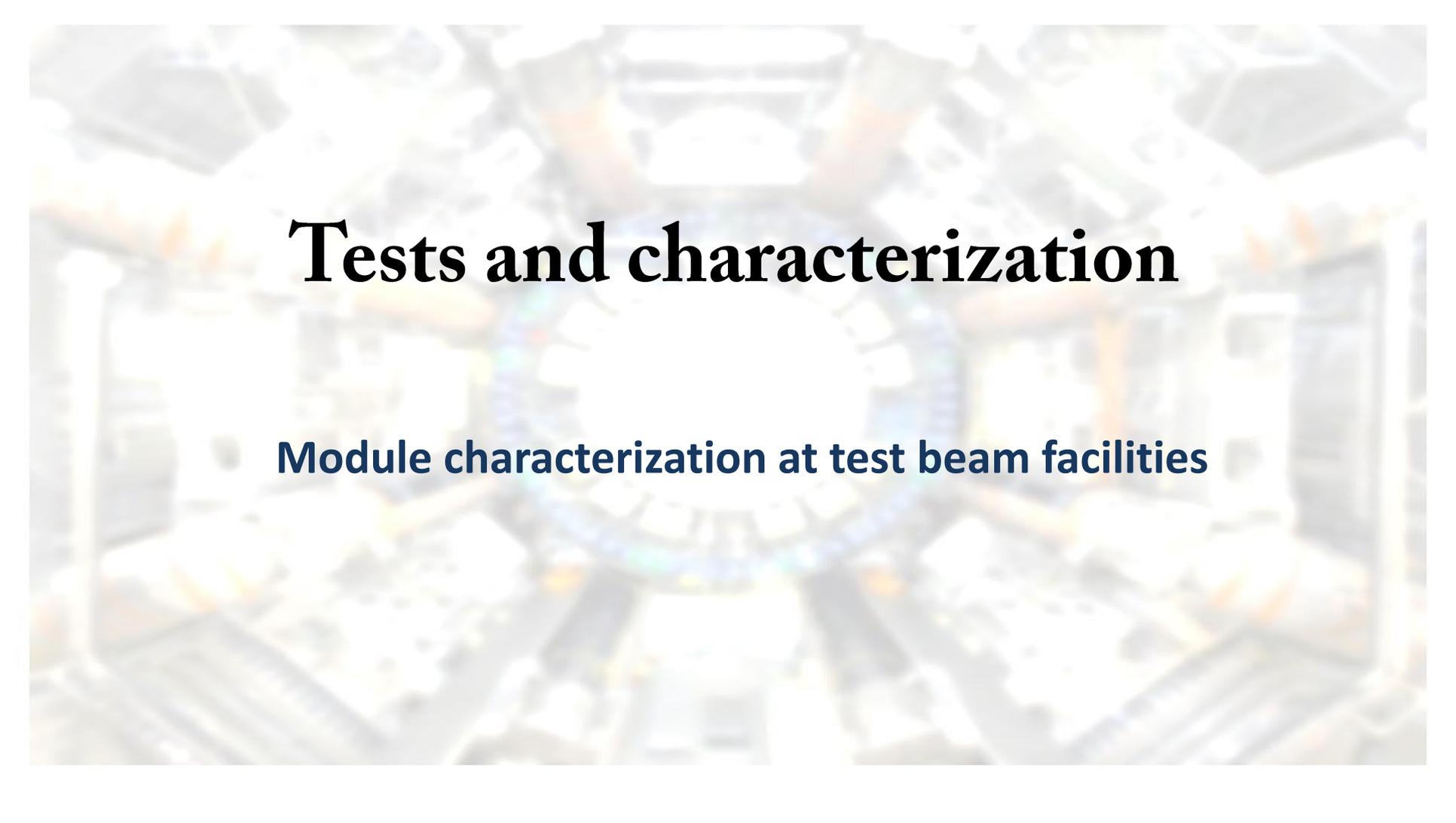
- Study the overall and edge hit efficiency with normal and inclined tracks before and after irradiation;

Active edge



Slim edge



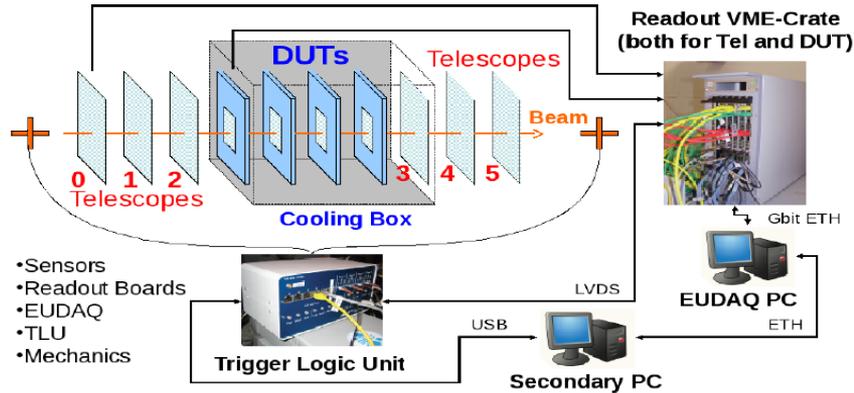
The background of the slide is a blurred, high-angle photograph of a complex, circular particle detector or accelerator component. The structure is composed of numerous metallic, cylindrical and rectangular segments arranged in a ring, with various internal structures and support beams visible. The lighting is somewhat dim, creating a technical and scientific atmosphere.

Tests and characterization

Module characterization at test beam facilities

Test beam characterization

Test Beam telescope setup:



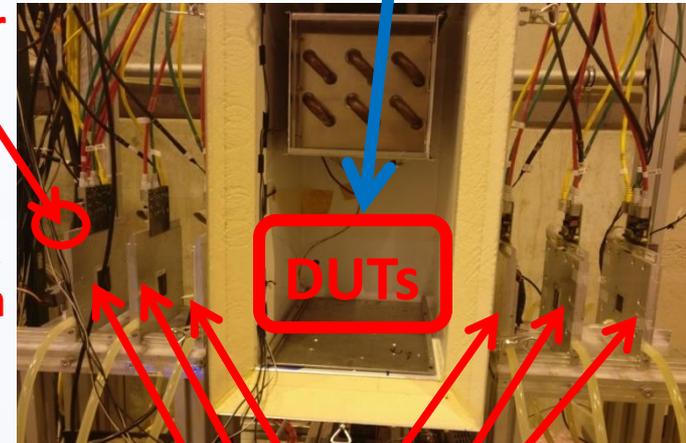
- Mimosa26 sensors (1152 x 576) with a pixel pitch of 18.4 μm ,
- 50 μm thick;
- Spatial resolution up to 2 μm ;
- Pixel read-out systems fully integrated into EUDAQ software framework;
- Multiple DAQ systems for lab tunings and measurements: USBPix, RCE, etc

EUDET telescope
ACONITE (H6A):



Scintillator

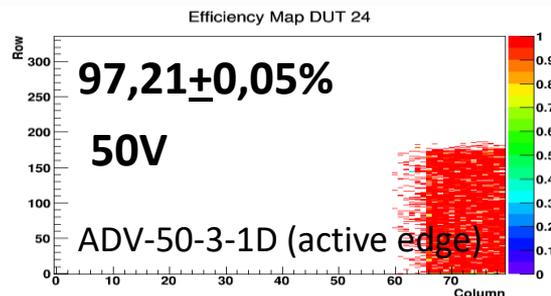
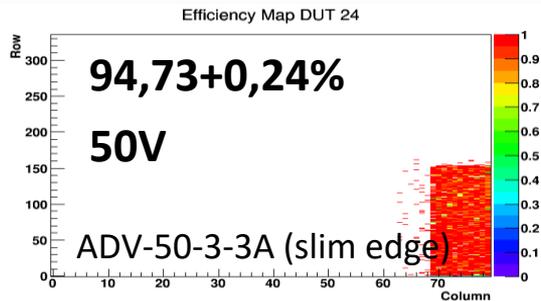
Beam



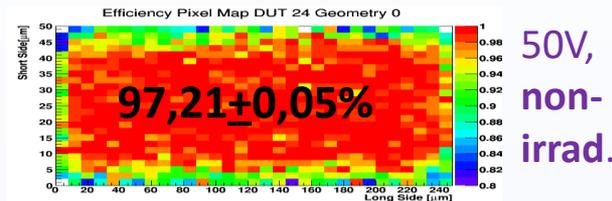
Test beam characterization results

- Hit efficiency calculated as :
$$\text{Efficiency} = \frac{\text{Number of Matched Tracks}}{\text{Number of Total Tracks}}$$

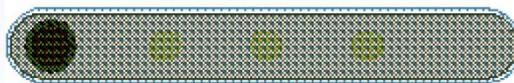
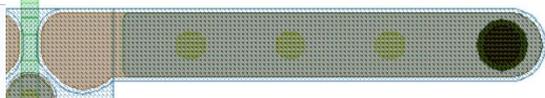
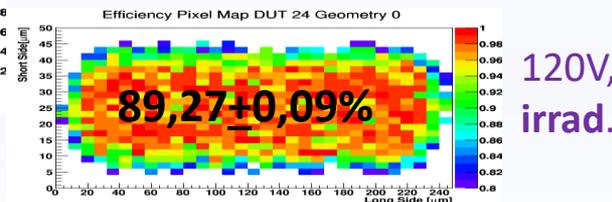
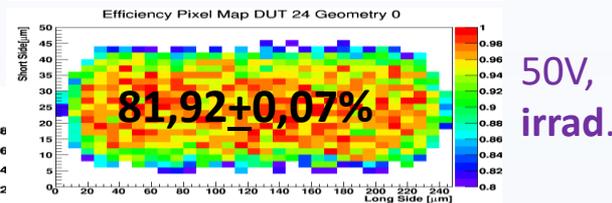
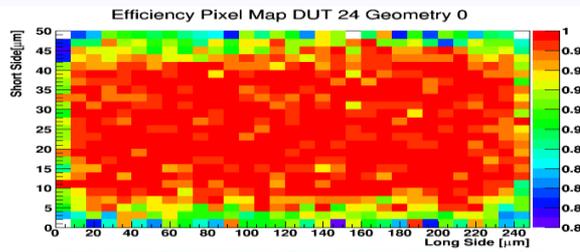
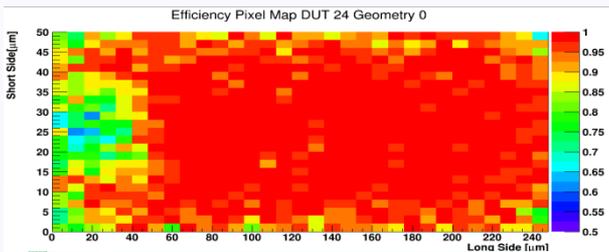
Overall efficiency



Non-irradiated and Irradiated,
 $1e15 \text{ n}_{eq}/\text{cm}^2$ ADVACAM sensors

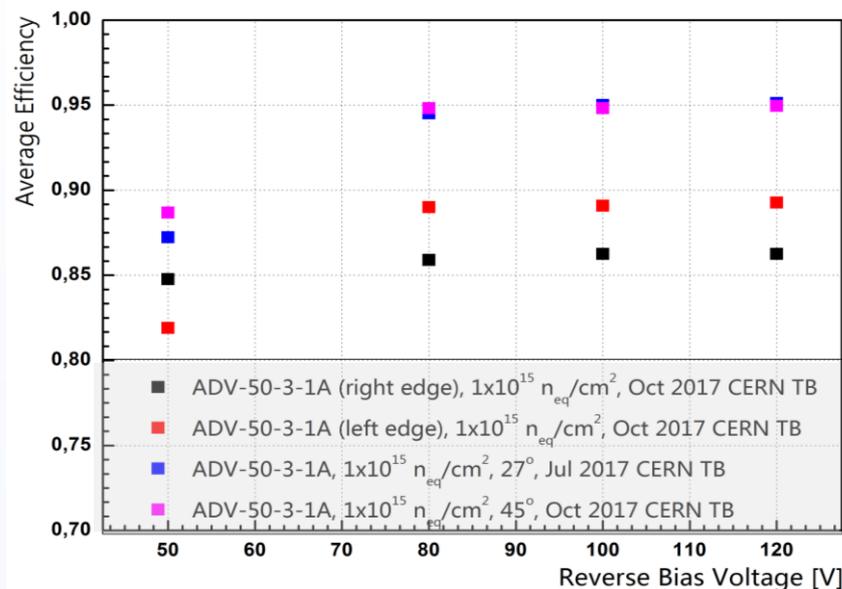
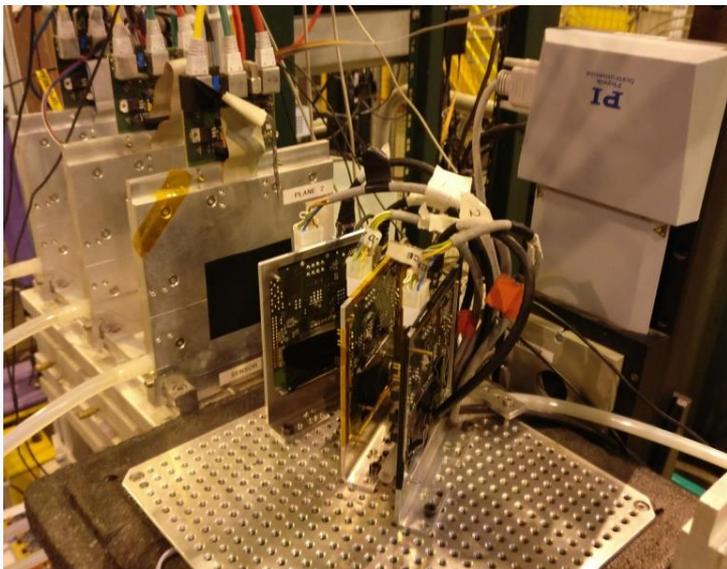


In-pixel efficiency



Test beam characterization results

- Efficiency vs bias voltage: $1e15$ n_{eq}/cm^2 , tilted (45° and 27°)



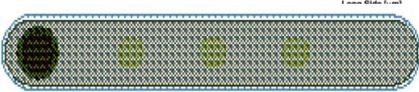
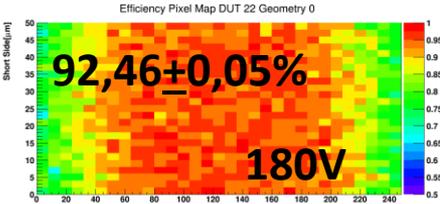
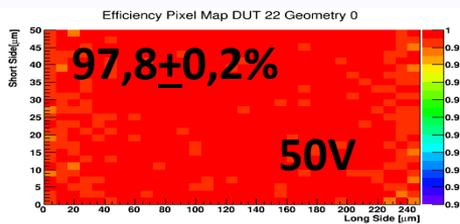
At a tilted angle of 45° , the efficiency performance improved, reaching 95% at 80V bias voltage. The performance is very similar to the performance at 27° case (but with dry ice cooling).

Test beam characterization results

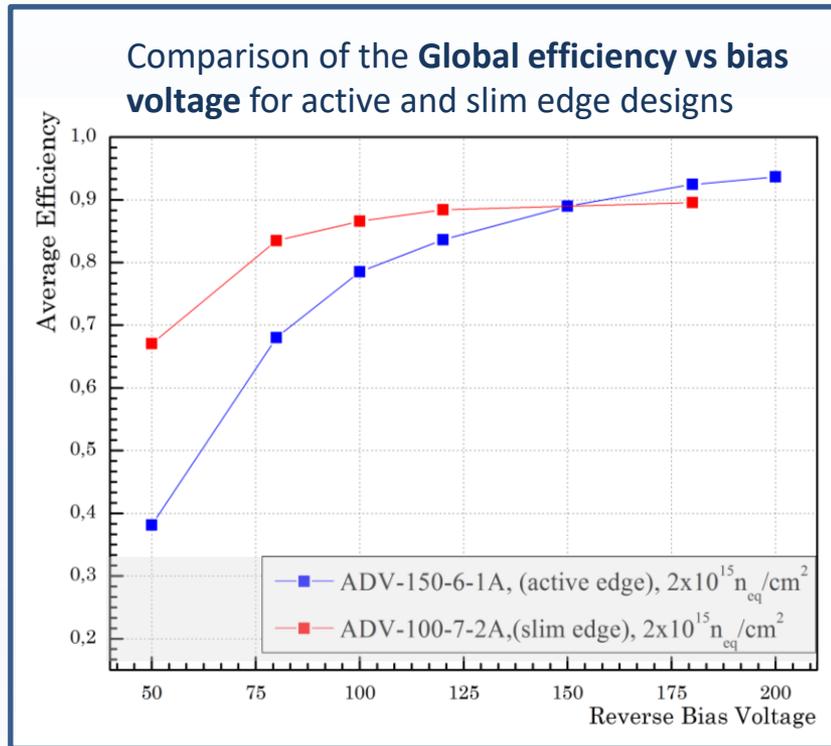
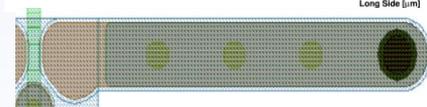
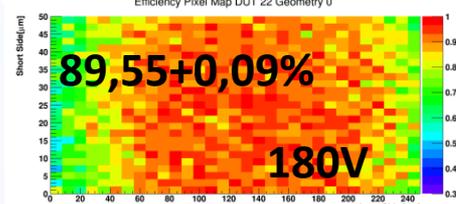
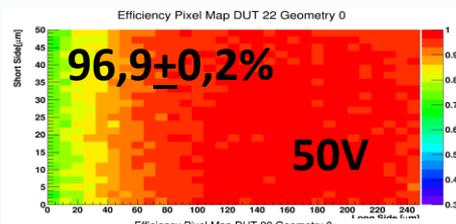
Efficiency performance for the **active edge (150 μm)** and **slim edge (100 μm)** after irradiation $2 \times 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$ at different bias voltages.

- In-pixel efficiency maps

Active edge



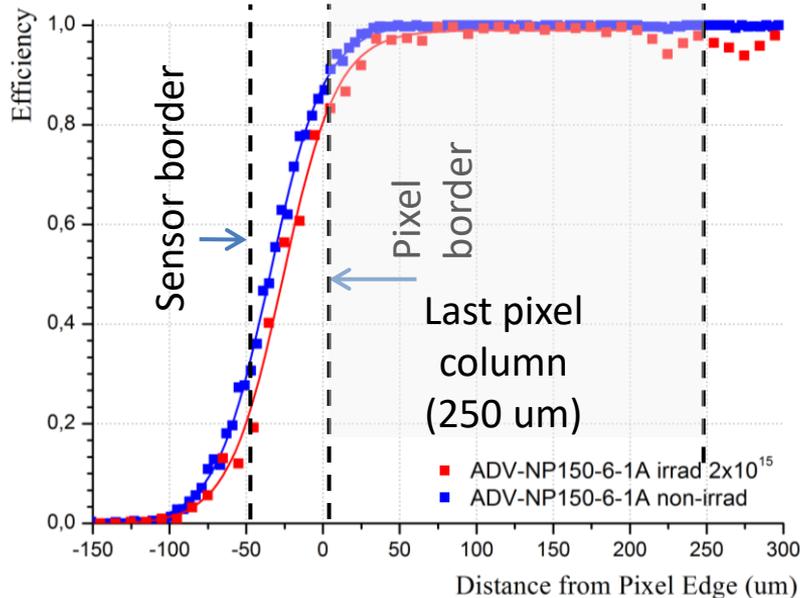
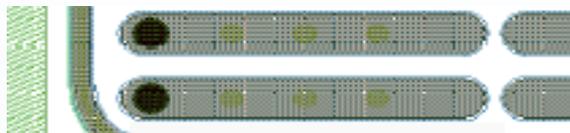
Slim edge



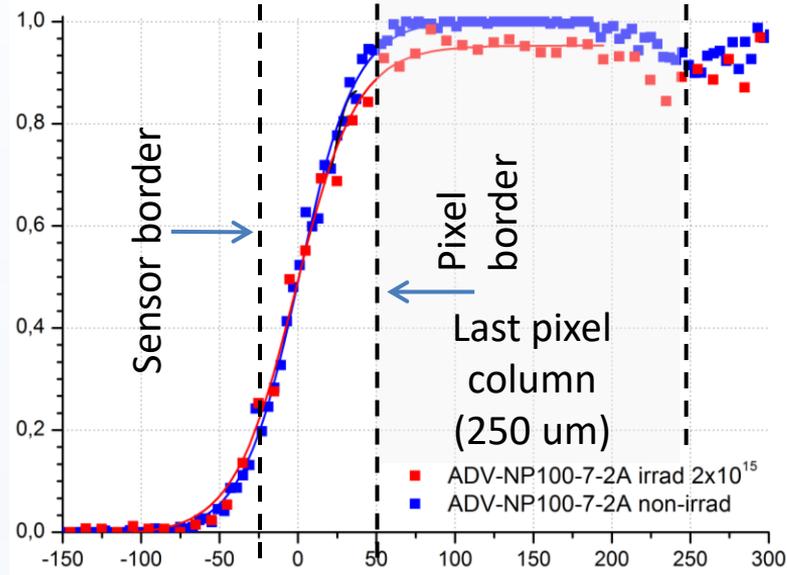
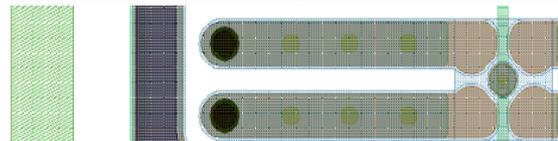
Test beam characterization results

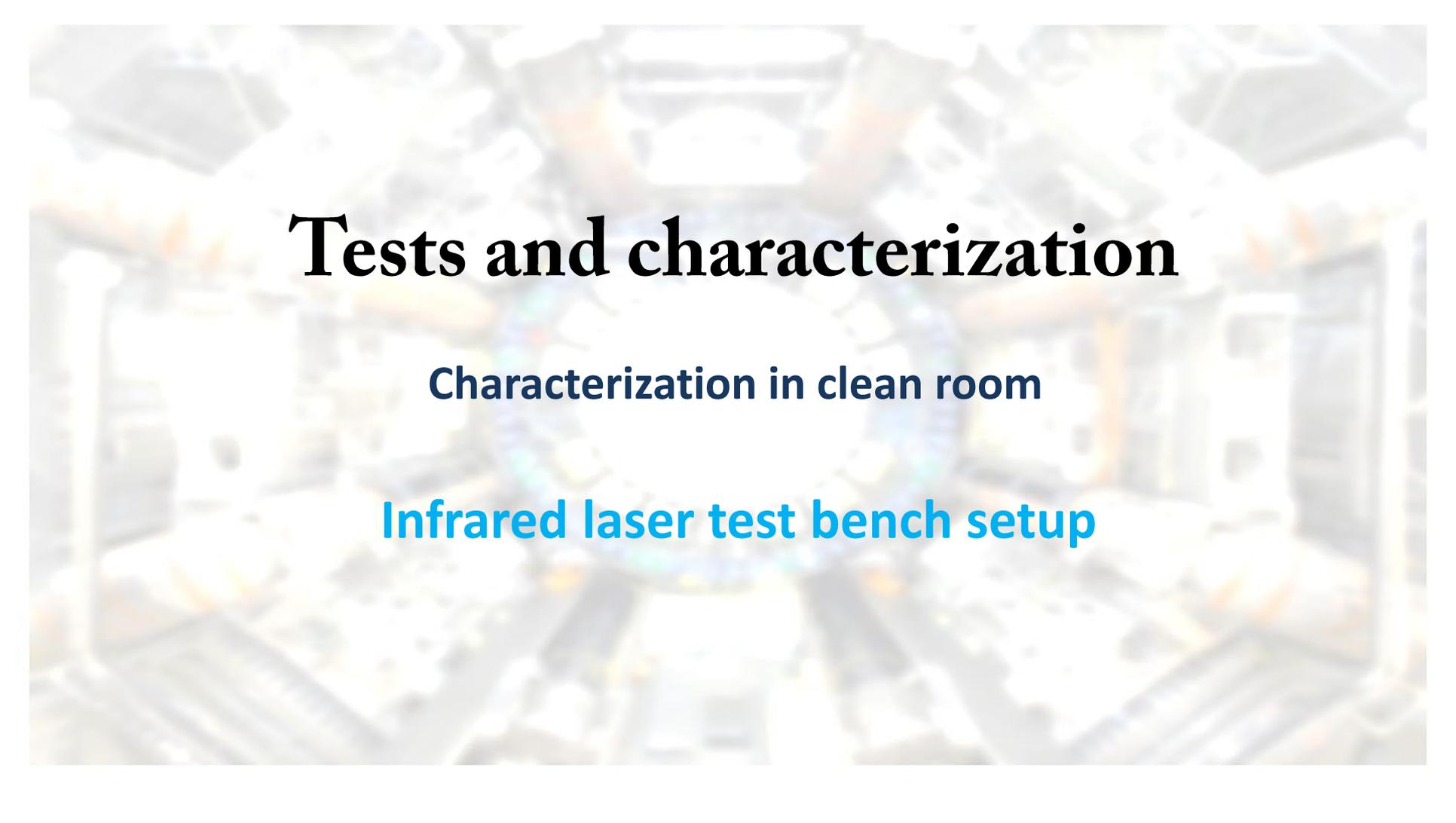
Efficiency performance for the **active edge (150 μm)** and **slim edge (100 μm)**

ACTIVE
EDGE



SLIM
EDGE





Tests and characterization

Characterization in clean room

Infrared laser test bench setup

Laser test bench setup

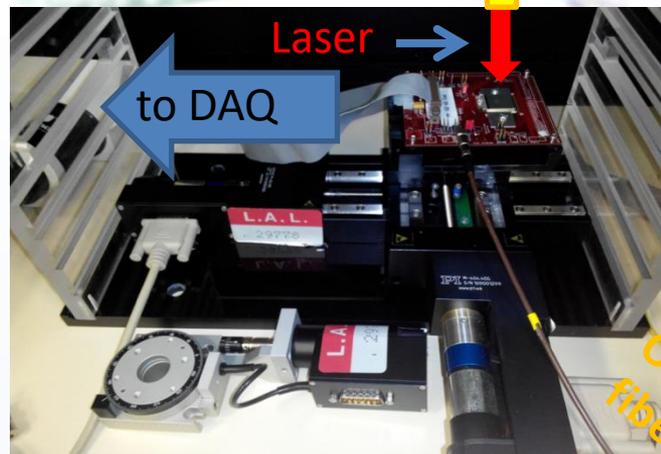
Purpose: To have a compact set-up to characterize silicon pixel modules and test their functionality in clean room before beam tests.

- charge collection efficiency (before and after irradiation, for the edges, scanning along an individual pixel);
- charge sharing between adjacent pixels;
- performance with inclined tracks;

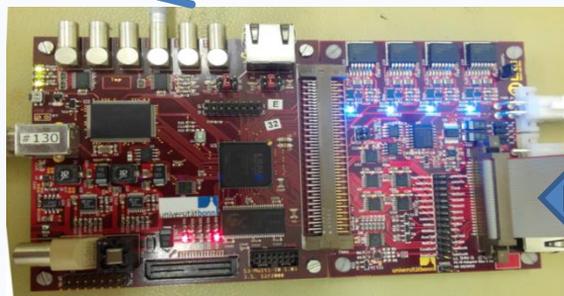
Our goals for this development:

- to have a setup based on infrared laser to mimic a MIP like charge generation;
- to have a possibility for micrometric positioning of the DUT in X-Y direction (so the interaction point determination without reconstruction);
- to be able to rotate a DUT to perform studies with inclined tracks;
- to adapt to new quad sensors and RD53-A readout electronics;
- have high rates (kHz), for high statistics in measurements;

Laser test bench setup



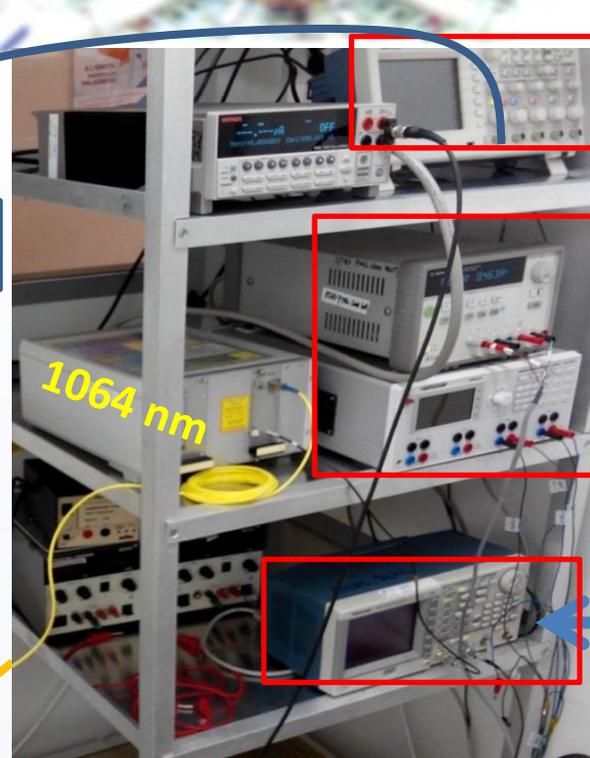
DAQ
system



From Module

O/E
converter

25%



Scope

Module Front-End
power suppliers

Function
generator

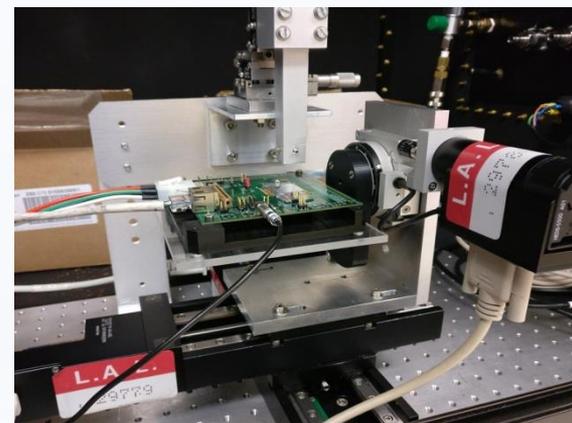
Bias HV for the
module

Laser test bench setup

LabVIEW software for the laser test bench controlling and parameters readout



DUT support with rotating stage

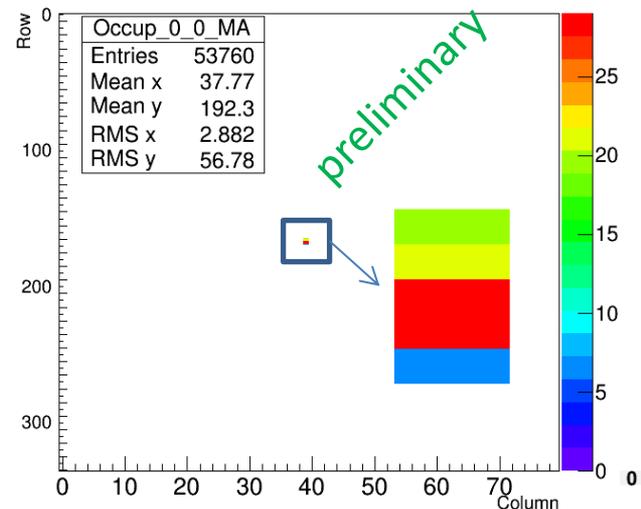
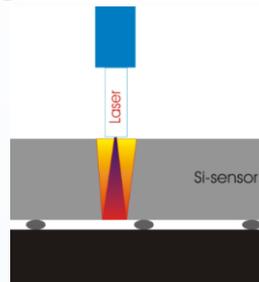
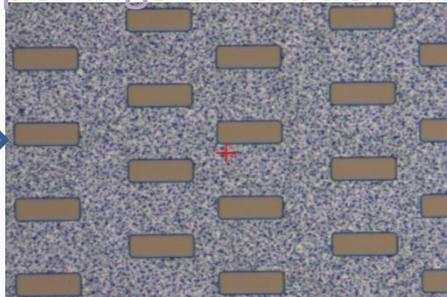
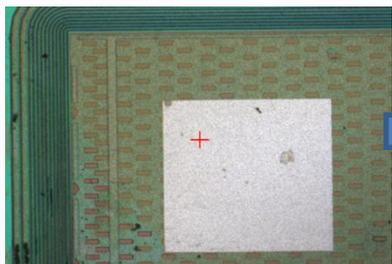


The screenshot shows the LabVIEW software interface for the laser test bench. It includes several control panels:

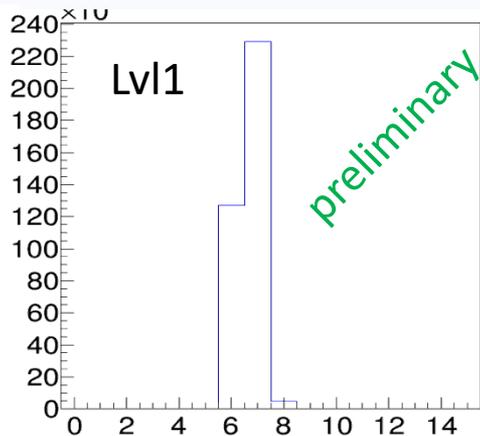
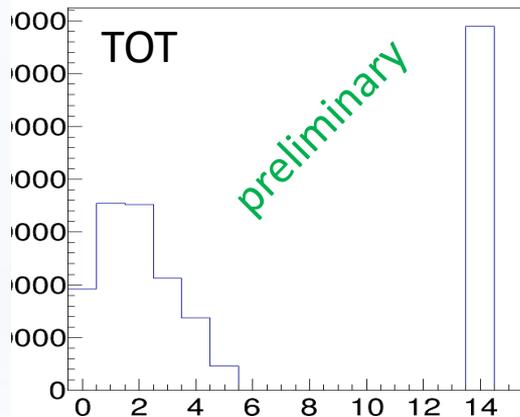
- Set Keithley Parameters:** Controls for KEITHLEY MODEL 2410, including Voltage Limit [V], Max Current [A], Current Limit, Delay time [sec], Polarity, and V-Source Value [V].
- Tektronix AFG3252:** Controls for the signal generator, including Channel, Frequency, Amplitude [V], Impedance, Width [-sec], Delay [usec], and Polarity.
- Agilent E3631A:** Controls for the power supply, including CH1 and CH2 Current Limit [A], CH1 Voltage [0-6V], CH2 Voltage [0-25V], and current readouts.
- Rohde&Schwarz HMP4040:** Controls for the precision multimeter, including PRESET, Channel, Voltage [0.0], Current [0.0], and current readouts.
- Waveform:** A graph showing a square wave signal with Amplitude [V] on the y-axis and Time [s] on the x-axis. Controls for HORIZONTAL and VERTICAL scaling are provided.
- X-Y Table:** Controls for the microscope stage, including Position, Absolute motion mode (X coord [mm], Y coord [mm]), Relative motion mode (X shift [um], Y shift [um]), and Offset point is: (47,950 40,870) [mm].
- Magnify:** A directional pad for magnifying the waveform.
- TIMER:** A digital timer showing 0,832938.

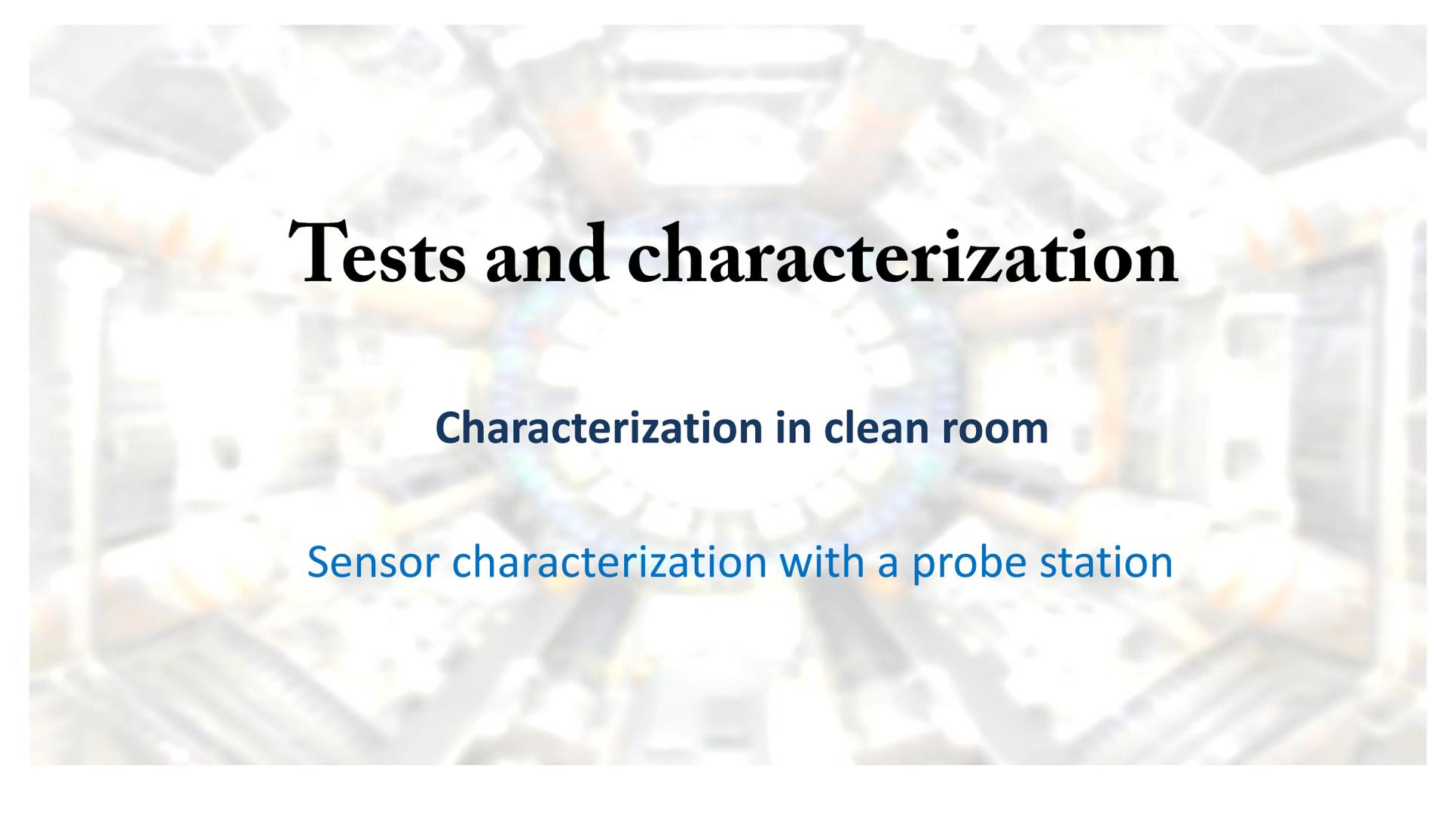
Laser test bench setup

Openings on a back side



Hit map with the visible laser spot.





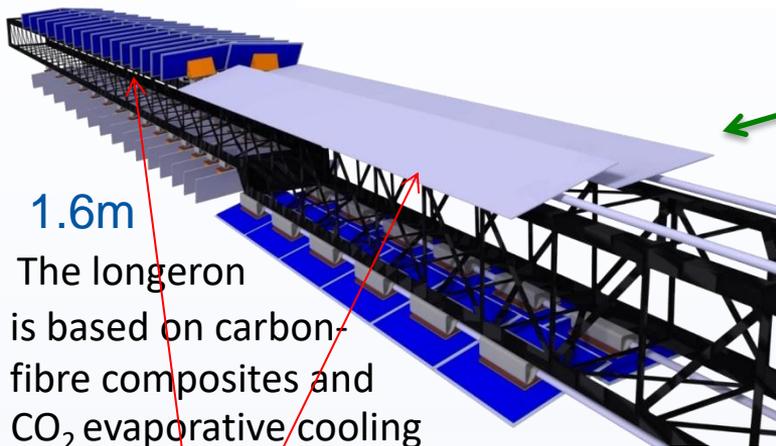
Tests and characterization

Characterization in clean room

Sensor characterization with a probe station

ITk Demonstrator project

The key goal is the demonstration of the system aspect of the complete and functional **ITK pixel barrel stave**.



1.6m

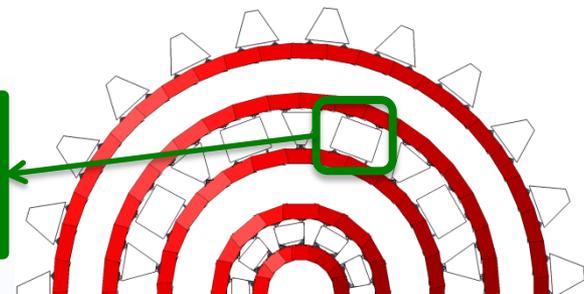
The longeron is based on carbon-fibre composites and CO₂ evaporative cooling in titanium pipes.

Module Cells are built with quad M4 (flat) and double-chip M2 (inclined)

Mockup heaters (minimum 48xM4 & 109xM2)

- Silicon heaters with embedded thermal sensors for thermal and thermo-mechanical testing
- Flexes to power the heaters & read the thermal sensors (similar to the actual electrical)

This is the element which we propose to build as "Stave-0"



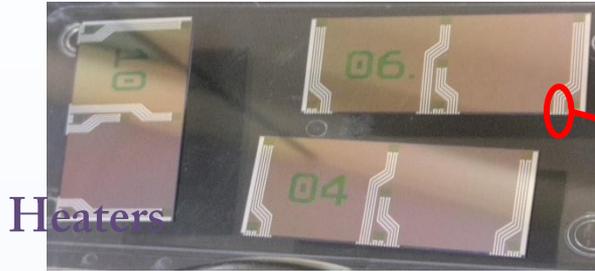
Build and test large scale, realistic prototype

Objectives:

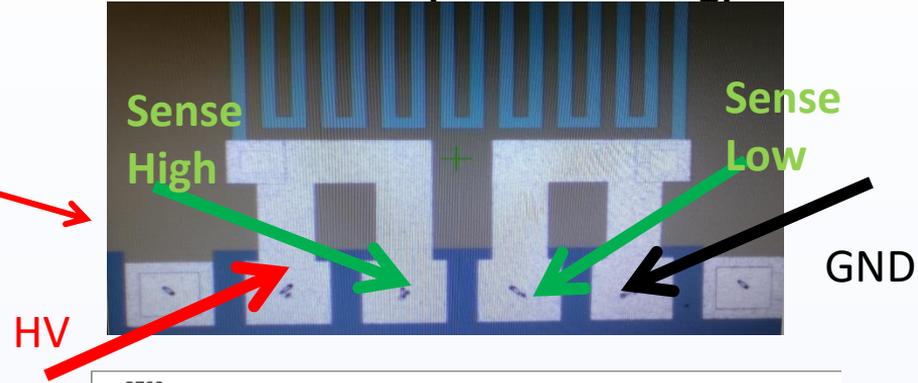
- *Validate local support concept*
- *Validate integration and electrical services*
- *Validate procedure for loading and survey*
- *Study thermal performance*

ITk Demonstrator project

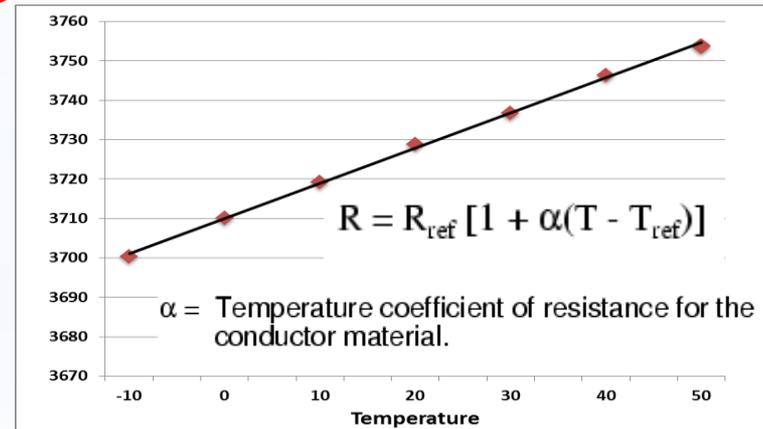
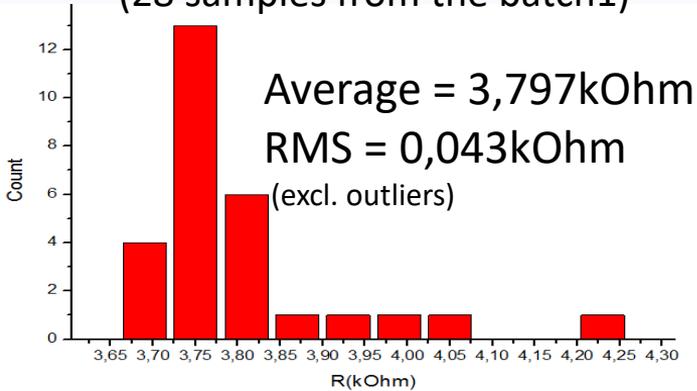
Thermal sensor characterization as a function of temperature



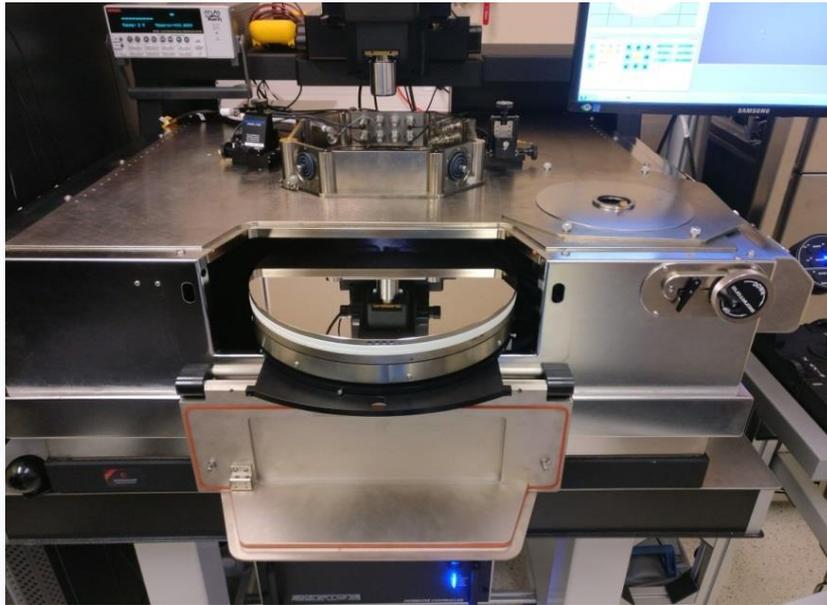
Four-terminal (Kelvin sensing)



Histogram of Resistance at 20°C
(28 samples from the batch1)



Heaters measurements

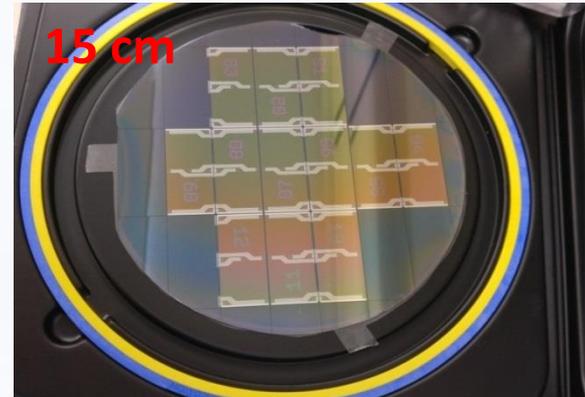


Semi-automatic probe station

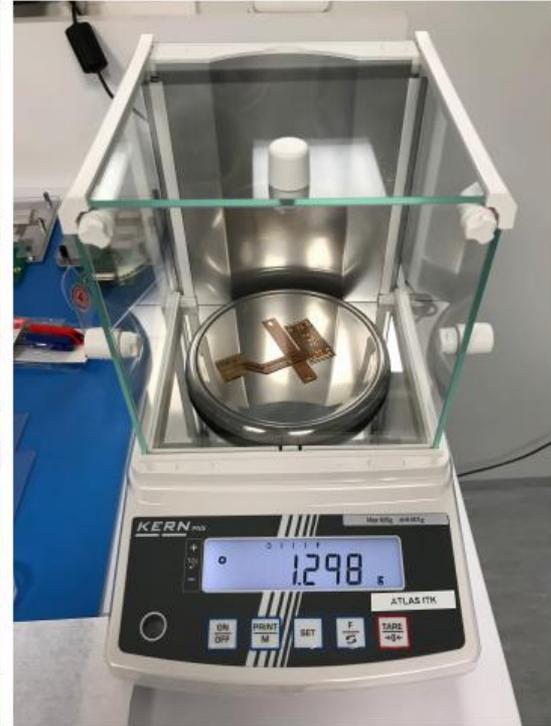
allows performing of IV and CV measurements.

- Cooling (-10° - 50° C)
- Allows measuring of the big wafers up to 30 cm in diameter

Heater samples for the
Demonstrator project



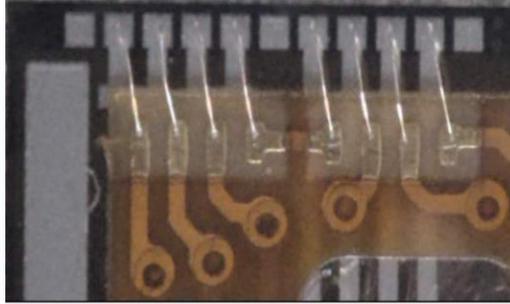
Heaters assembly



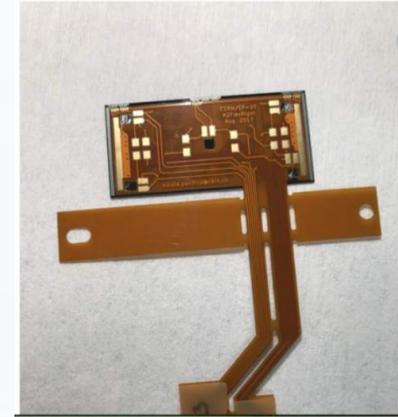
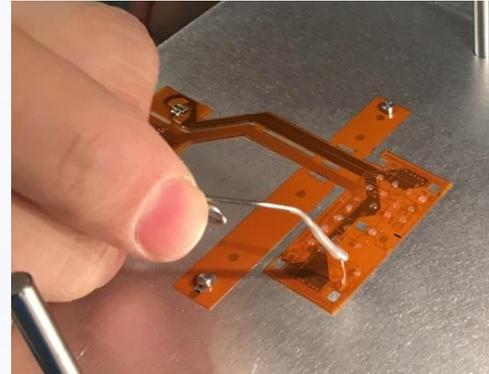
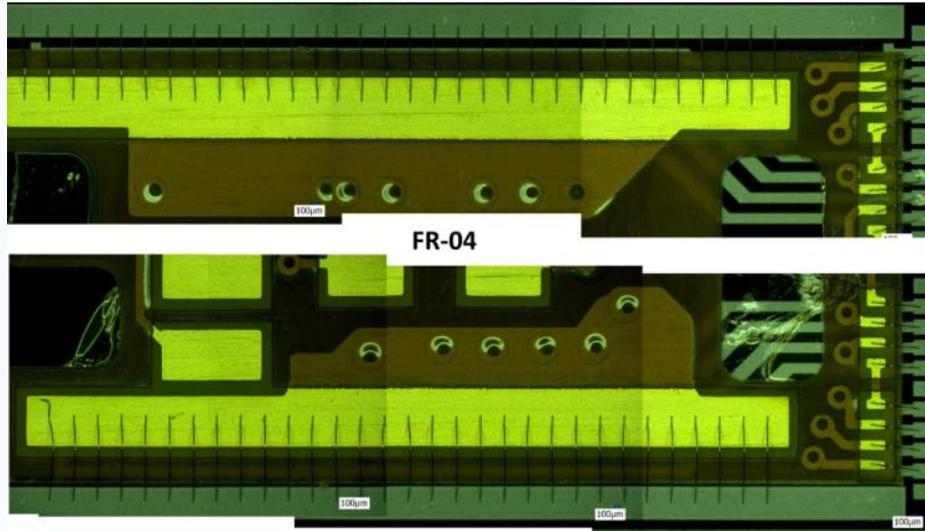
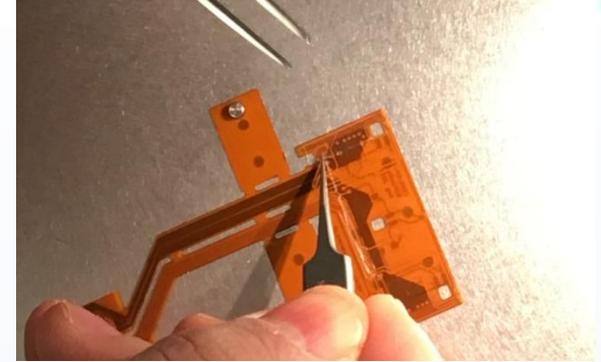
Gluing setup with 2 flex jigs + 2 sensors bridges

Heater assembly

Wire-bonding
at Saclay



Gluing →



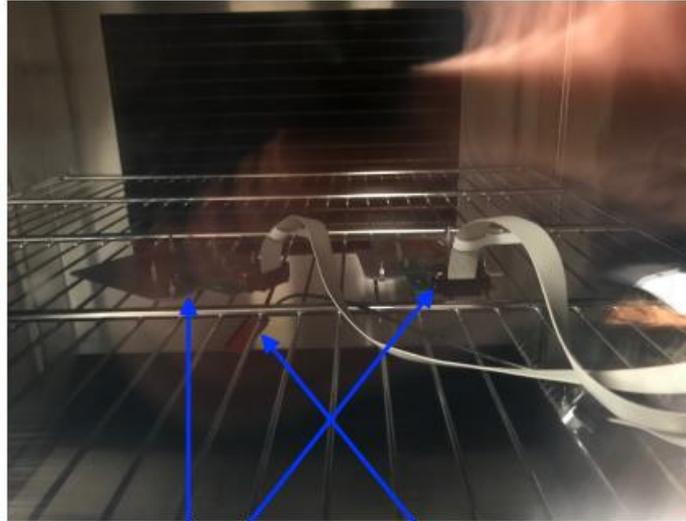
5/29/2018

Calibration setup



climate chamber

Keithley
2410



modules

PT100

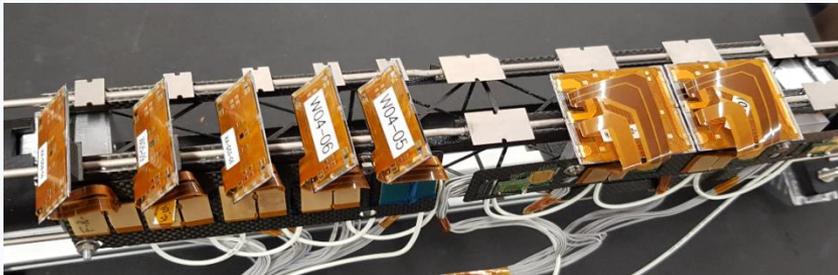
- R cross-checked with 3 different instruments;
- T cross-checked with PT100 attached to sensor put inside the climate chamber
- 4 cables => calibrate 4 modules in parallel

Assembly & transportation



- 20 thermal modules were successfully glued wire-bonded and tested.
- Have been weighted before/after gluing as requested;
- Cleaned in ultrasonic bath in isopropanol at 50°C and 12h 120°C in the oven;

Integration on the long thermal demonstrator



Summary and Conclusions

- In view of the fact that in the framework of HL-LHC project it is planned to increase the integrated luminosity by a factor of 10, we will face the problem of extremely high pile-up and radiation-harsh environment. Therefore we have to build new tracker (ITk) that is expected to perform at least as well as the current one (and often better) despite the much harsher conditions.
- The various designs of sensor candidates for the ITk upgrade have been tested at test beam. The efficiency performance has been estimated.
- A new setup for laser tests in a clean room has been developed in a preliminary form. The system was adjusted, and first results were obtained, but the laser test system has to be improved.
- Demonstrator project is an important step towards building of the ITk. Considering a short timeline of the project we have to do an intensive work on thermal tests with heater modules.

Thank you for your attention!

BACKUP Slides

Results

Comparison of the performance of active and slim edge design sensors:

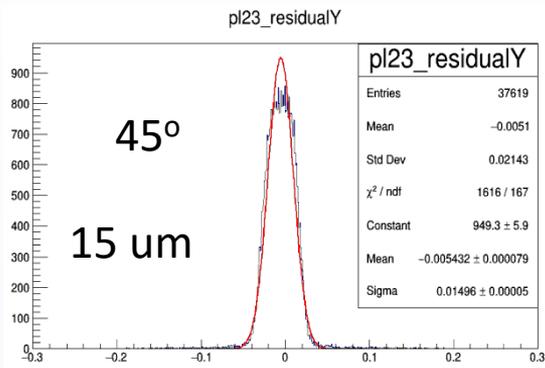
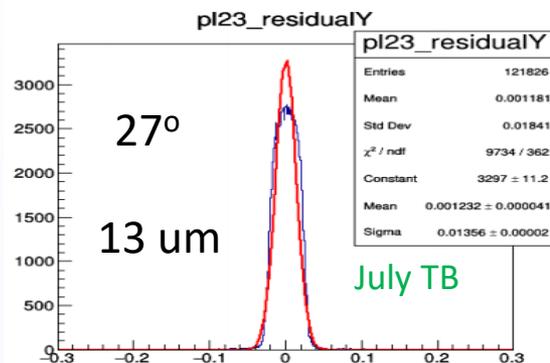
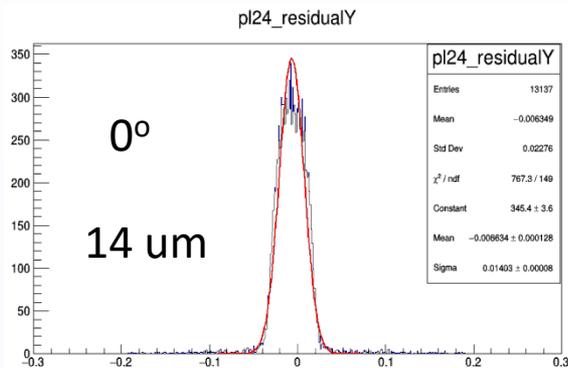
- 50 um – thick sensors:
 - Before irradiation active edge shows efficiency of 97,2% while slim edge has 94,7% (50V);
 - At $1e15 n_{eq}/cm^2$, the efficiency of active edge is 86-89%, while slim edge is 79-84% at 120V.
- 100 um slim edge sensor :
 - Before irradiation provides 96,8% of hit efficiency (50V);
 - After irradiation at $2e15 n_{eq}/cm^2$ the efficiency can recover 89.5% at 180V;
- 150 um active edge sensor:
 - Before irradiation provides 97,8% of hit efficiency (50V);
 - After irradiation at $2e15 n_{eq}/cm^2$ the efficiency can recover 93.6% at 200V;

Both designs had an issue during TB with the achievement of high voltage (breakdown starts and sensor becomes noisy)

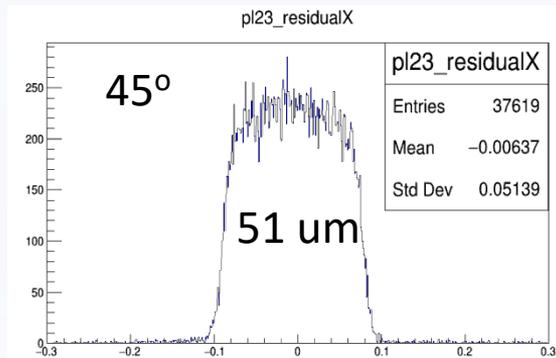
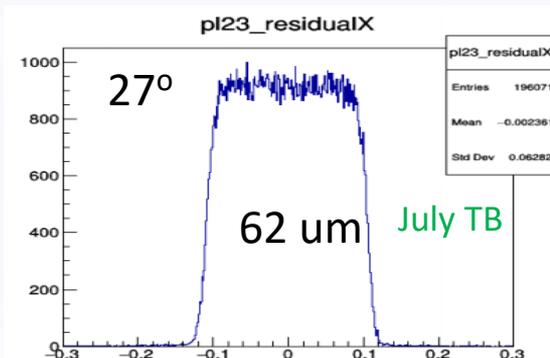
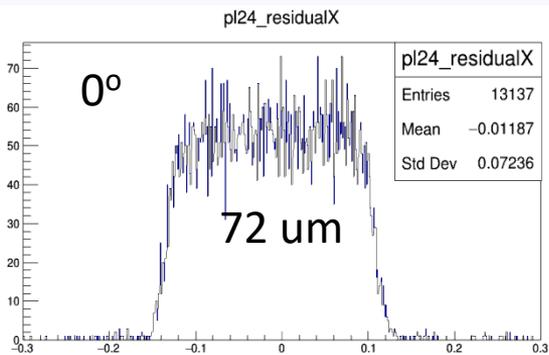
Test beam characterization results

- Residuals comparison at different orientation angle to the beam

Short side :



Long side :



Test beam characterization

Our Goal:

- Investigate the performance of the n-in-p planar pixel sensors with the active and slim edge design produced by **ADVACAM** before and after irradiation;
- Study the overall and edge efficiency with normal and inclined tracks.

- Hardware

- Telescope at CERN
- 120 GeV pion beam

- Software

- Reconstruction: EU Telescope (*Data conversion, Cluster finding, Hitmaker, Alignment, Track fitting*)
- Analysis: TBmon2 (Efficiency, charge sharing, residuals, ToT, etc)

• Normal incidence

- Bias voltage points: 50 V, 80 V, 100 V, 120 V
- Cooling box (-40°C to -44°C)
- Dry ice cooling (approx. -40 to -50 °C*)

• Inclined tracks

- DUT tilted at 45° (around y-axis)

* Only indirect temperature measurements available

Goals

- Efficiency for **50 μm -thick ADVACAM samples** with **active edge** and **slim edge** design
 - with and without irradiation $1 \times 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$;
 - on different side edges;
 - with **normal** and **inclined** incident (DUT tilted at 30° , 45° (around y-axis));
- Efficiency for **100 μm -thick ADVACAM sample** with **slim edge** design before and after irradiation $2 \times 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$;
- Efficiency for **150 μm -thick ADVACAM sample** with **active edge** design before and after irradiation $2 \times 10^{15} \text{ n}_{\text{eq}}/\text{cm}^2$;

Beam: CERN SPS 120 GeV pions, DESY 4 GeV electrons;

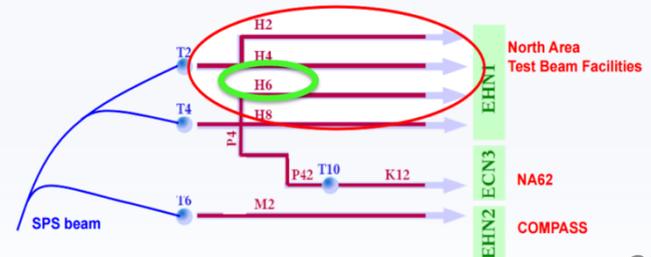
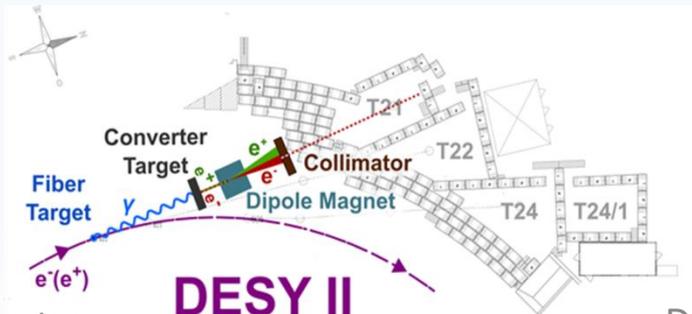
Telescopes: DURANTA (TB22) , ACONITE (H6A) and AIDA (H6B);

Cooling: Cooling box (-40°C to -44°C), Dry ice cooling (approx. -40 to -50°C);

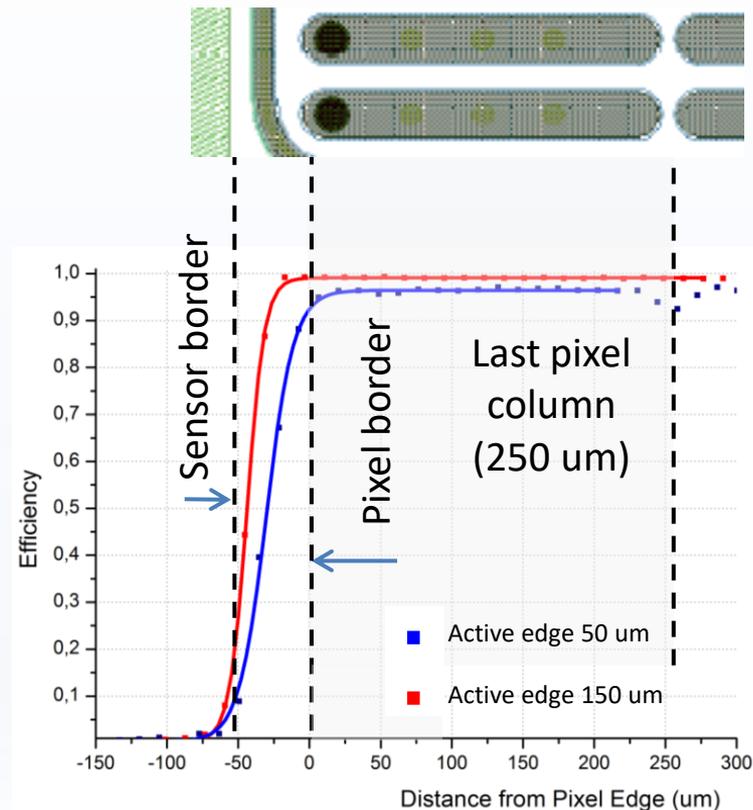
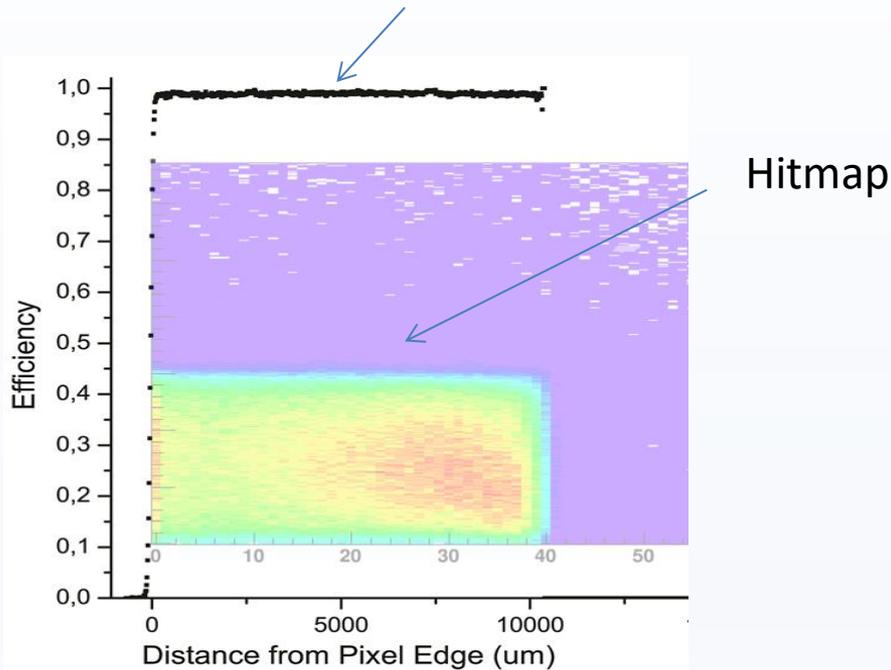
Bias voltage points:

from 50 V to 120 V (for 50 μm);

from 50V to 200V (100 μm ,150 μm)



- Efficiency vs track impact position



Test beam characterization results

- *Efficiency vs track impact position*

